

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No. 09/298,160
Filing Date April 22, 1999
Inventor Dan G. Custer et al.
Assignee Micron Technology, Inc.
Group Art Unit 1746
Examiner A. Olsen
Attorney's Docket No. MI22-1172
Title: Polishing Systems, Methods of Polishing Substrates, and Methods of
Preparing Liquids for Semiconductor Fabrication Processes

RESPONSE TO OCTOBER 22, 2001 OFFICE ACTION

To: Box Non-Fee Amendment
Assistant Commissioner for Patents
Washington, D.C. 20231

From: Bernard Berman (Tel. 509-624-4276; Fax 509-838-3424)
Wells, St. John, Roberts, Gregory & Matkin P.S.
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Sir:

Responsive to the Office Action dated October 22, 2001, Applicant respectfully requests reconsideration of the above-referenced application in view of the amendments and remarks that follow.

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